

| | Type | Hits | Search Text | DBs | Time Stamp | C o m m e n t s | E r r o r D e f i n i t i a l i z e d | E r r o r R e f e r e n c e s |
|---|------|------|--|---|------------------|--------------------------------------|---|---|
| 1 | BRS | 848 | abrasive with ((first and second) adj3 (material or layer or coat\$3 or cover\$3)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 13:28 | | | 0 |
| 2 | BRS | 130 | ((abrasive with ((first and second) adj3 (material or layer or coat\$3 or cover\$3))) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 13:29 | | | 0 |
| 3 | BRS | 74 | ((abrasive with ((first and second) adj3 (material or layer or coat\$3 or cover\$3))) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5)))) and @pd<=20020926 | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 13:30 | | | 0 |
| 4 | BRS | 0 | ((abrasive with nanoporous) same (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 15:09 | | | 0 |
| 5 | BRS | 2 | ((abrasive with nanoporous) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 15:11 | | | 0 |
| 6 | BRS | 5 | ((abrasive or particle\$s) with nanoporous) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 15:17 | | | 0 |
| 7 | BRS | 3 | ((abrasive or particle\$s) with nanoporous) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) not ((abrasive with nanoporous) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5)))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 15:12 | | | 0 |
| 8 | BRS | 5 | ((abrasive or particle\$s or slurry) with nanoporous) and (cmp or ("chemical mechanical" adj (polish\$3 or planariz\$5))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/05/10 15:17 | | | 0 |